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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**

Norio KIMURA et al. : Docket No. 2001-0660A

Serial No. 09/864,208 : Group Art Unit 1763

Filed May 25, 2001 : Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD : **MAIL STOP: AF**

RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1763

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents

P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of May 16, 2005, kindly amend the above-referenced
U.S. patent application as follows: